

Optical reflectance-based software for automated characterization of nanomaterials: outcomes of the NSF Nanohub's NanoMFG node

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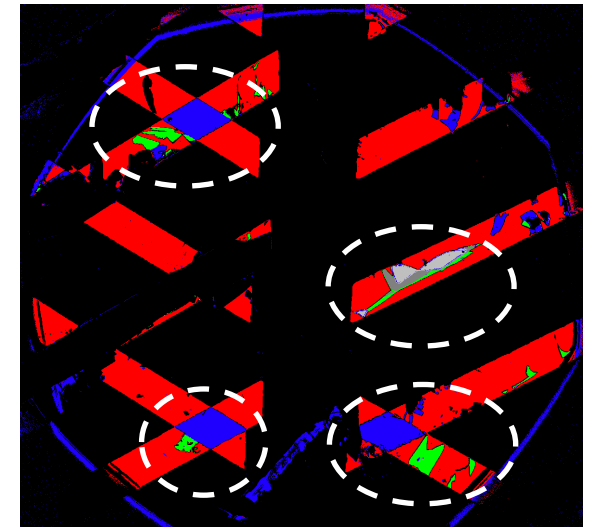
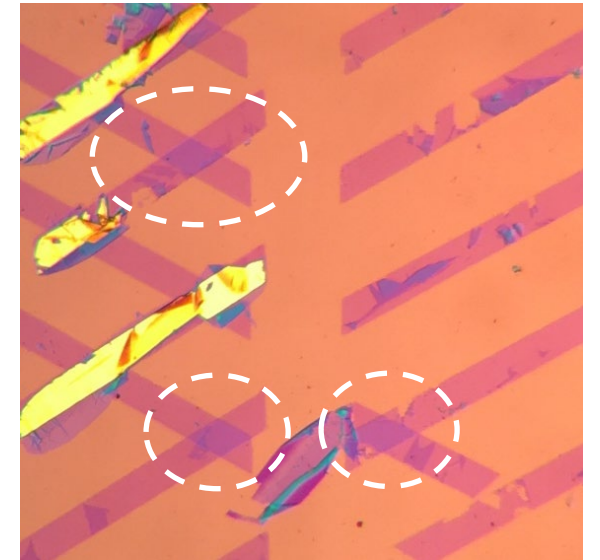
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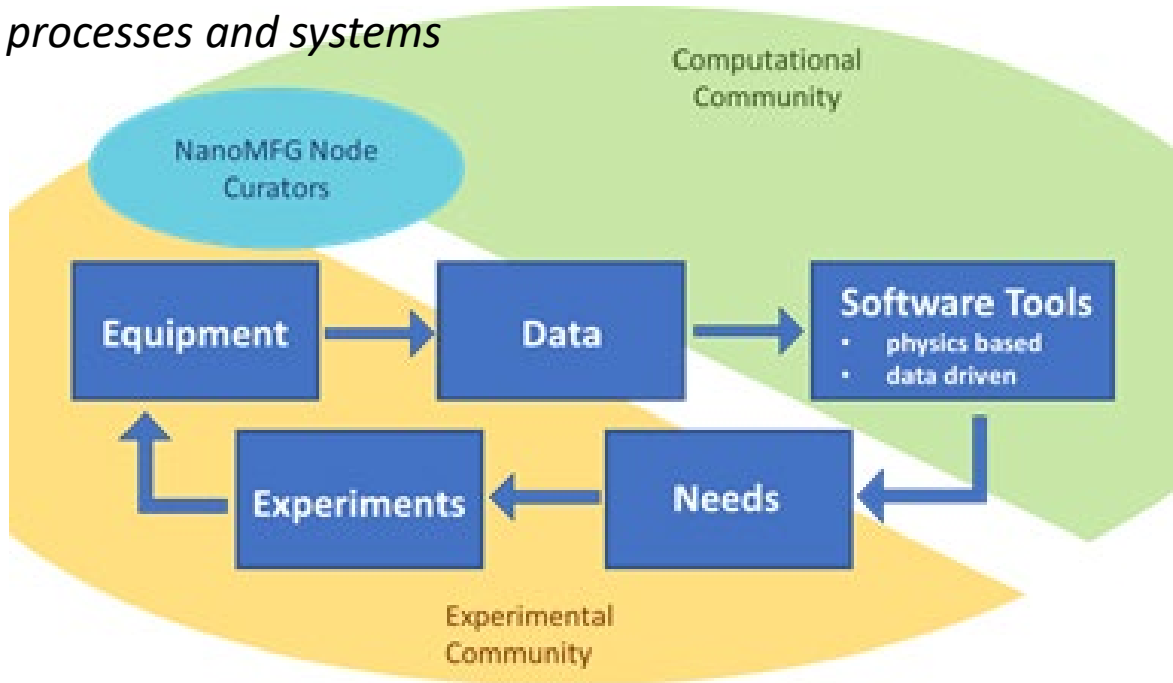
Outline: NSF nanoMFG node outcomes

- Introduction to the NSF nanoMFG node
- Nanomanufacturing simulation needs survey
- Two recently released nanoMFG tools:
applications of optical reflectance in
nanoscale characterization
 - In-situ viscosity determination for nanoimprint
resists: *nanovisc*
 - Determination of 2D material heterostructure
composition: *2dreflect*
- Future areas of interest



nanoMFG – the NSF nanomanufacturing node

Vision: The nanoMFG node aims to assemble, develop, and implement advanced cyberinfrastructure tools for research, education, and industrial deployment of integrated, nanoscale manufacturing processes and systems



Goals:

- Develop and deploy software tools and make them available through the NCN-Cyber Platform (“nanoHUB”)
- Engage with the nanomanufacturing community to address critical needs
- Address the challenges of integrating data from the computational and experimental community
- Provide a streamlined process for software development



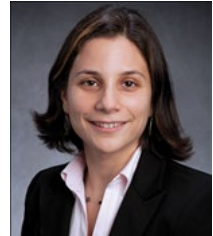
Adams



Aluru



Bauer



Ertekin



Ferreira



Katz



Roloff



Taylor

HIGHLIGHTED ACTIVITIES

Enabling Software for the Nanomanufacturing Community

Community Outreach

Data-Science Enabled Advances in Nanomanufacturing (DSEAN) Workshop

Getting involved with nanoMFG

Workshop on Data-Science Enabled Advances in Nanomanufacturing

- ✓ Annual workshop held in Febr/Mar
- ✓ Bring together members of the nanoMFG community from industry, labs, and academia
- ✓ Presentations, hands-on activities, panel discussions, poster sessions, and networking



Call For Tool Proposals

- ✓ Focuses on a targeted need for the nanomanufacturing community identified in Needs Assessment Report
- ✓ Includes full support for a graduate research assistant or partial support for a post-doc
- ✓ Includes two weeks onsite to work with our software development team on site; continued support for remote development
- ✓ Call released annually in early spring for next academic year

Opportunities for Students

- ✓ Opportunities for graduate students
- ✓ Two-year graduate fellowship for URM students
- ✓ Summer fellowships at Illinois and Berkeley
- ✓ Research Experience for Undergraduates via NCSA FoDOMMaT, NCN SURF



The nanoMFG node is committed to promoting diversity and providing an inclusive environment for all participants. Students, post-docs, and faculty from backgrounds traditionally underrepresented in STEM are especially encouraged to apply.

Questions? contact ertekin@illinois.edu or jayr@illinois.edu

Nanomanufacturing simulation needs survey

- Help us to shape the next phase of simulation tool development
- Paper survey in your conference materials; collection box at registration desk
- Also available online: <https://bit.ly/2VCsWRg> or use QR:
- Looking to schedule one-to-one conversations as well
- Contribute your free-to-use nanomanufacturing simulation tools to the Nanohub and get a citable DOI

nanoMFG

Nanomanufacturing simulation
needs survey 2019



Thank you in advance for taking the time to complete this survey/request for information. The NSF Nanohub's Nanomanufacturing Node (nanoMFG), <https://nanohub.org/groups/nanomfg>, seeks to build a sustainable infrastructure for the creation of high-quality, free-to-use nanoscale simulation software tools. We are currently surveying the NNT community to discover unmet simulation needs that will inspire the next phase of our work.

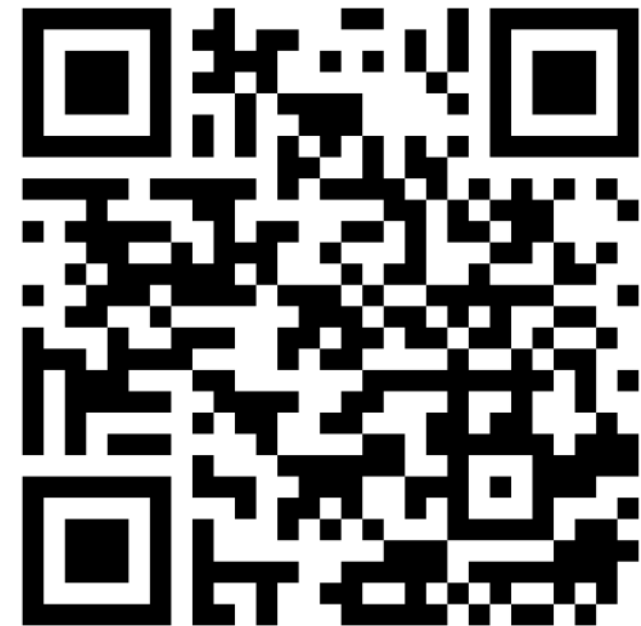
If you'd rather complete this survey online, you can do so at <https://bit.ly/2VCsWRg> or via the above QR code (please complete either the paper or online version, not both).

We are also keen to speak directly with anyone who has views or ideas surrounding nanoscale simulation software. Please drop Prof. Hayden Taylor a line (hkt@berkeley.edu or telephone/text 510 646-3344) and he would be grateful for an opportunity to speak with you, either in person at NNT or remotely at a later date.

1. Please check any areas below where you believe there are unmet needs for simulation software ('simulation' can be interpreted broadly):

NIL pattern formation including residual layer uniformity
 NIL stamp/template layout and design checking
 NIL demolding process or template lifetime prediction
 NIL overlay/process-induced distortions

Nanoscale aspects of injection molding
 Planarization
 Plasma etch processes
 Optical propagation in photonic materials/structures



diffraction optics
position, particularly of 2D materials
w-D materials: e.g. nanowires, graphene
ification
ig relating to nanofabrication processes
cribe below)

a few words describing what you

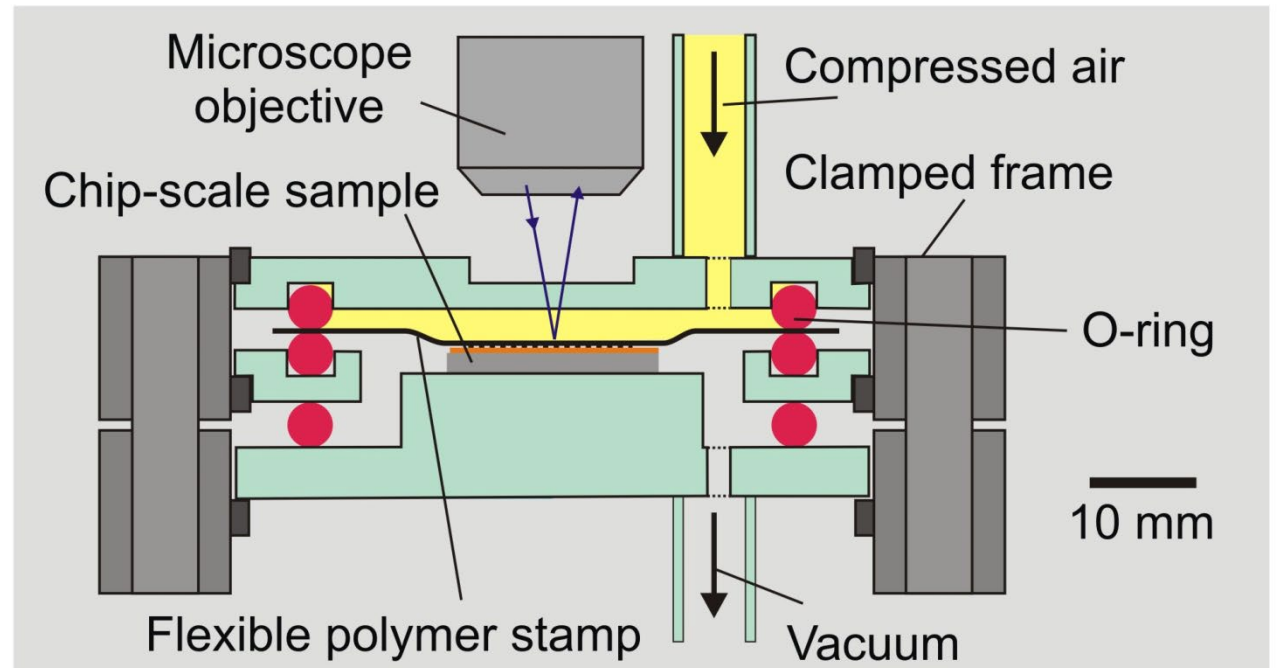
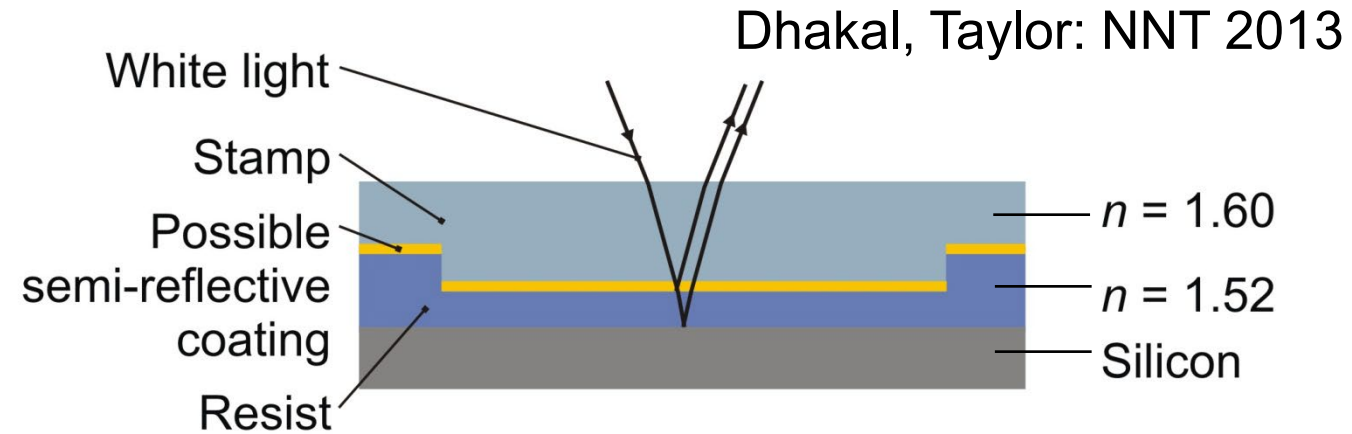
am used tools or materials from

NSF Network for Computational

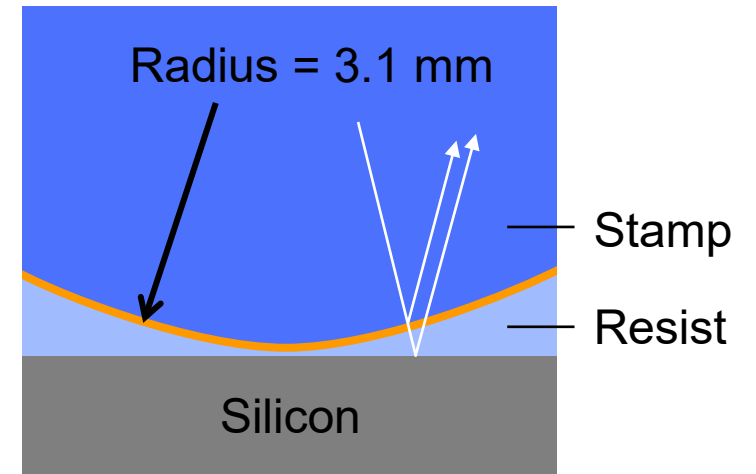
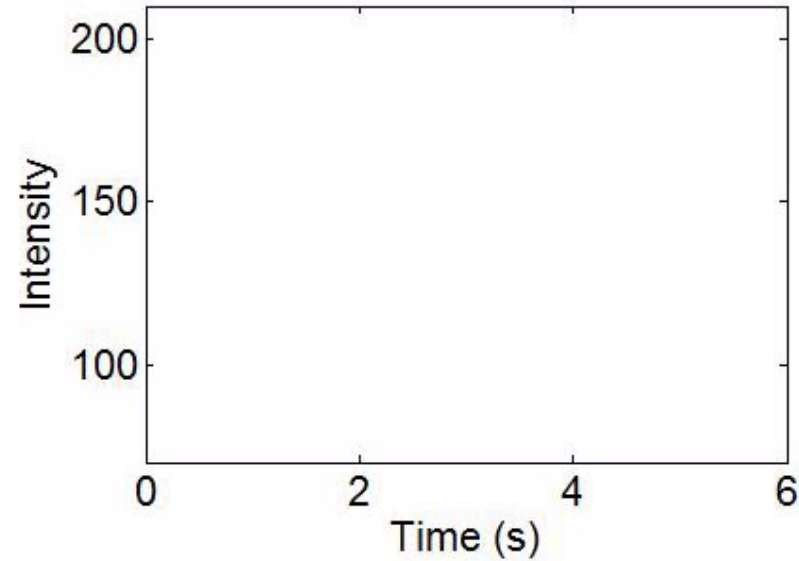
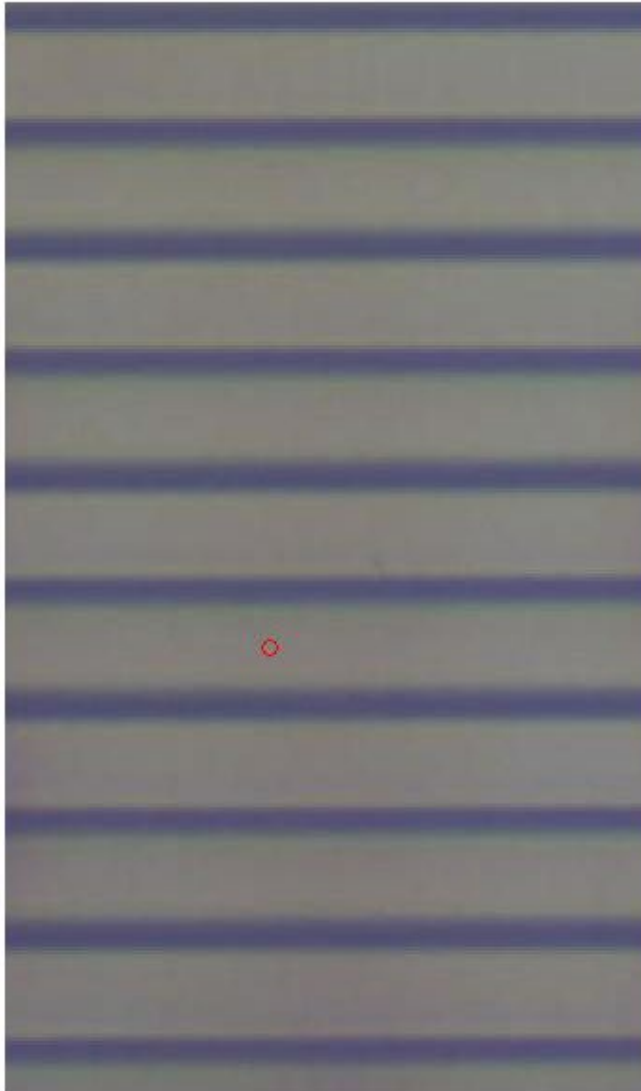
lation in addressing a particular
ion alone and/or hand analysis)?

Viscosity measurement of nanoscale-thickness films

- Need to determine rheological behavior in realistic environment:
 - Molecular confinement
 - Solvent evaporation extent
 - Solid-liquid boundary conditions
- Approach: observe squeezing flow of resist via optical reflection through stamp
- Pair intensity maxima/minima with modeled RLT values
- Extract viscosity by relating temporal RLT evolution to squeeze-film model

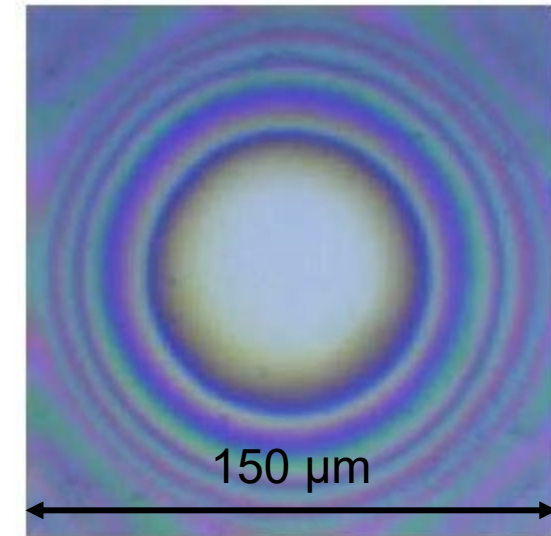


Viscosity measurement of nanoscale-thickness films



- **Material: MRT mr-UVCur-21**
- **Stamp-average pressure 20 kPa**
- **Consistent with viscosity ~ 7 Pa.s**

- ***But:* calibration with a known thickness set is needed for white light illumination**



Dhakai, Taylor: NNT 2013

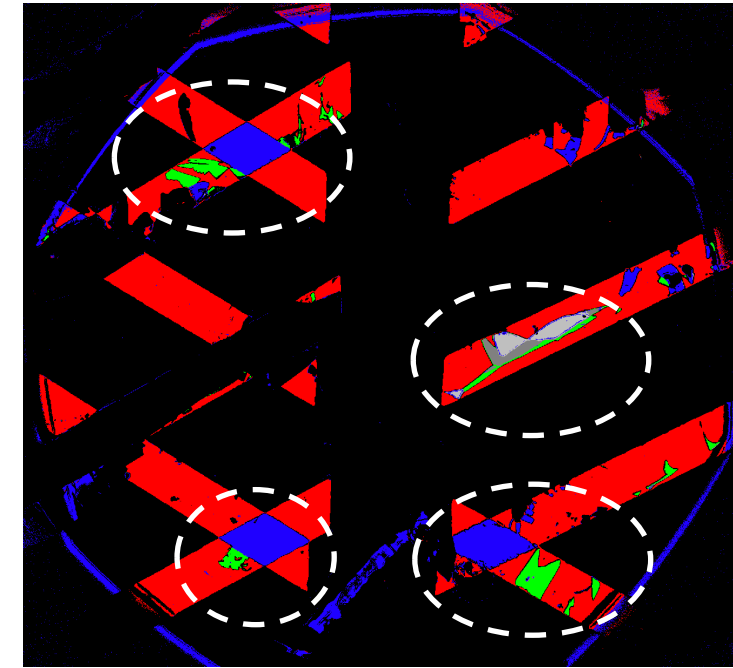
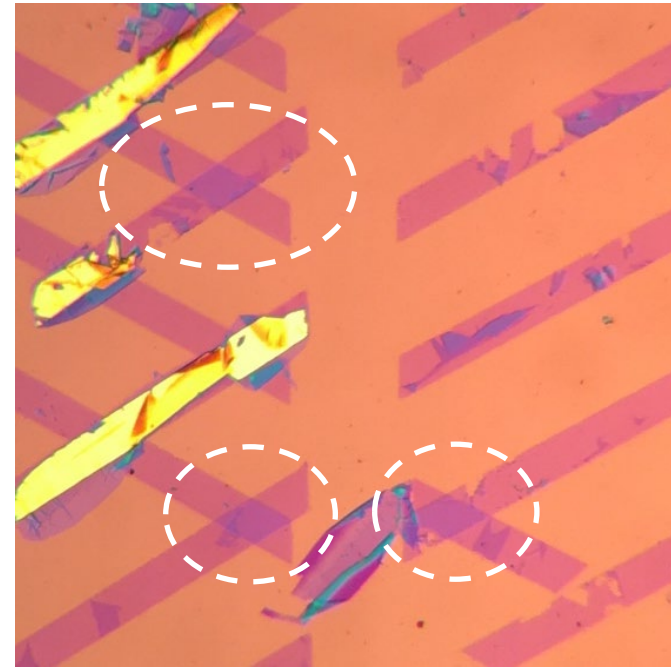
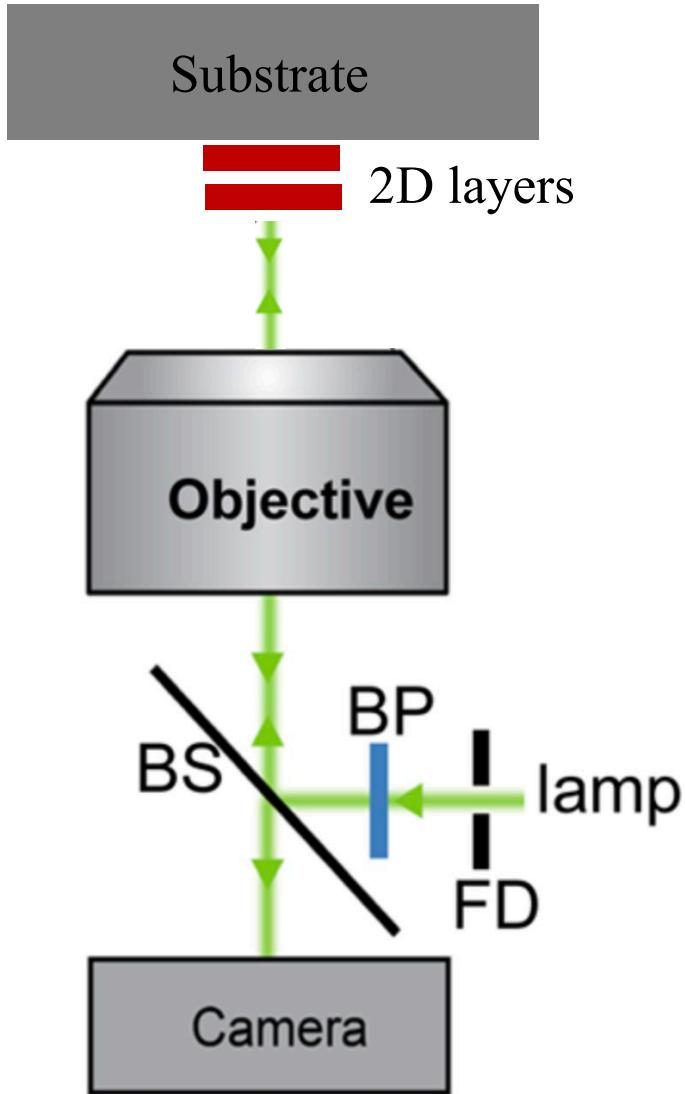
Viscosity measurement of nanoscale-thickness films

- Solution: two well spectrally separated LEDs (e.g. red, blue).
- One wavelength only
→ ambiguous RLT
- Two wavelengths → *sequence* of maxima and minima
unambiguously determines RLT
- *Nanovisc*:
 - imports video of squeezing
 - guides max/min identification
 - extracts viscosity



Reflectance-based characterization of 2D stacks

Two crossed arrays of MoS₂ by mechanical stacking

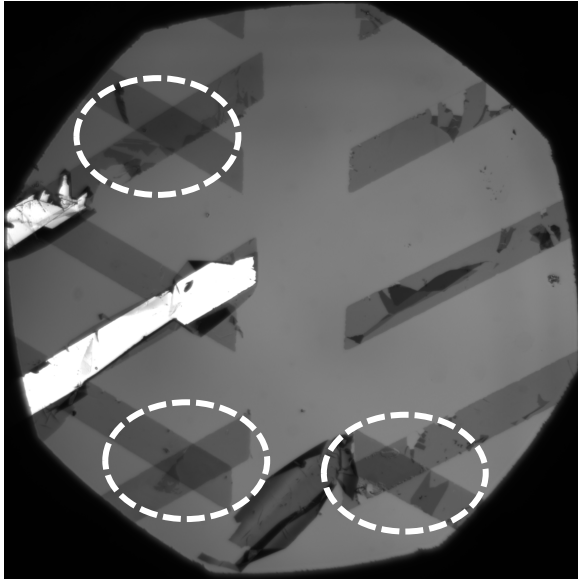


- substrate
- 1 layer
- 2 layer-natural
- 2 layer-stacked
- 3 layer-natural
- 4 layer-natural

validated by AFM and photoluminescence

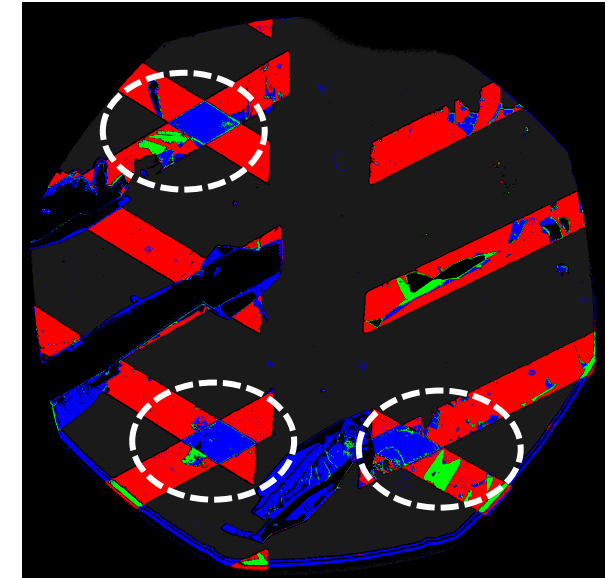
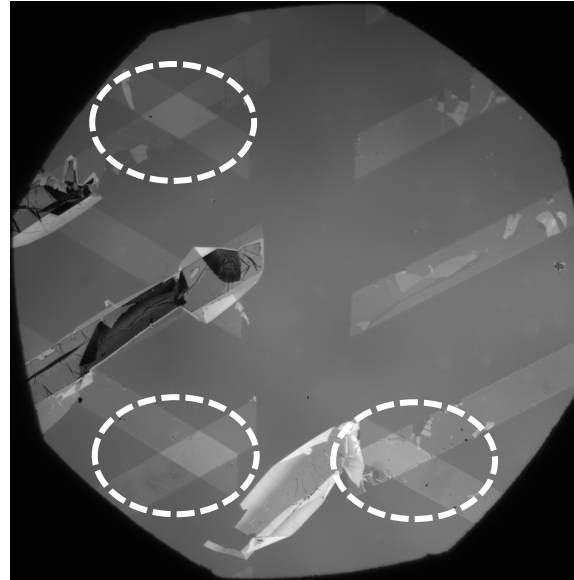
Distinguishing *natural* from *manufactured* bilayer MoS₂

610 nm illumination



+

450 nm illumination



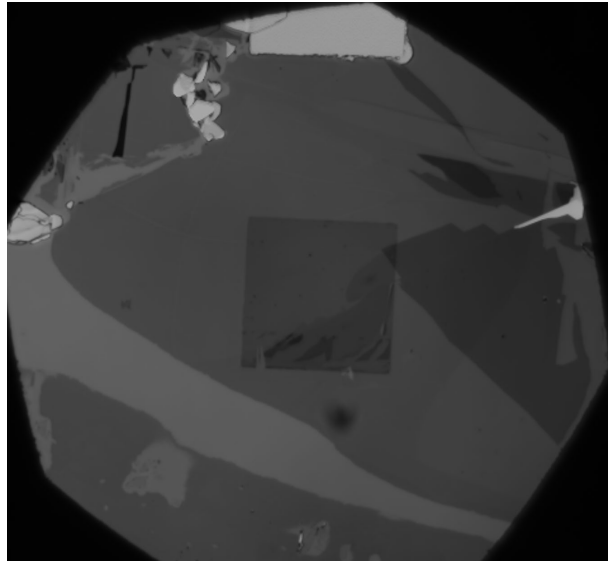
- High contrast between monolayer and bilayer
- Low contrast between closely and less closely spaced layers

- Low contrast between monolayer and closely spaced bilayers
- High contrast between closely and less closely spaced bilayers

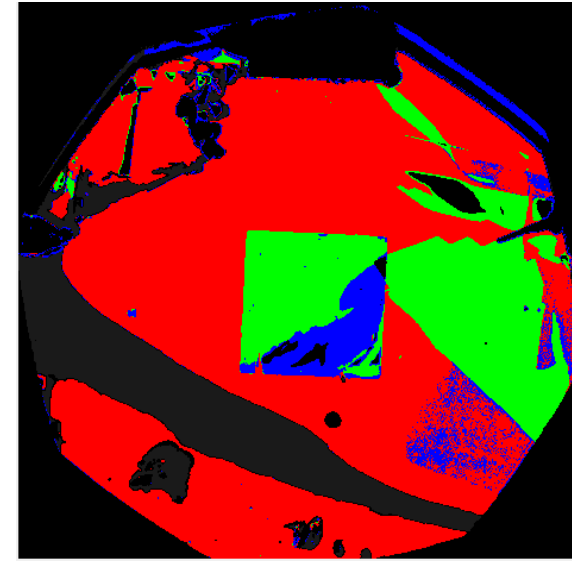
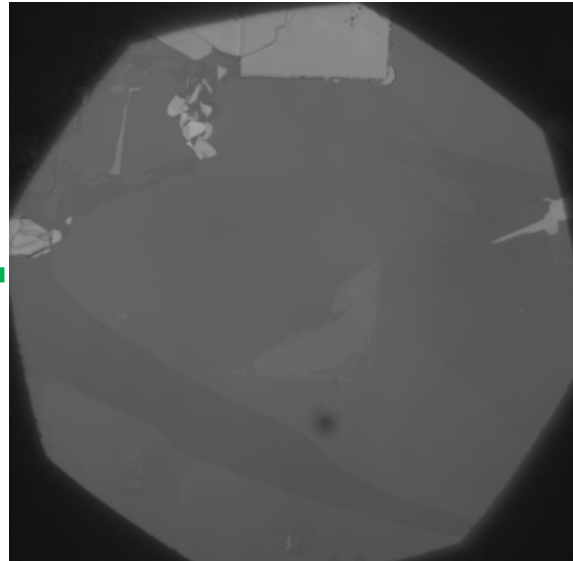
- Substrate (260nm SiO₂/Si)
- 1 layer MoS₂
- 2 layers, closely spaced
- 2 layers, less closely spaced

The impact of bilayer thermal annealing can be visualized

610 nm illumination

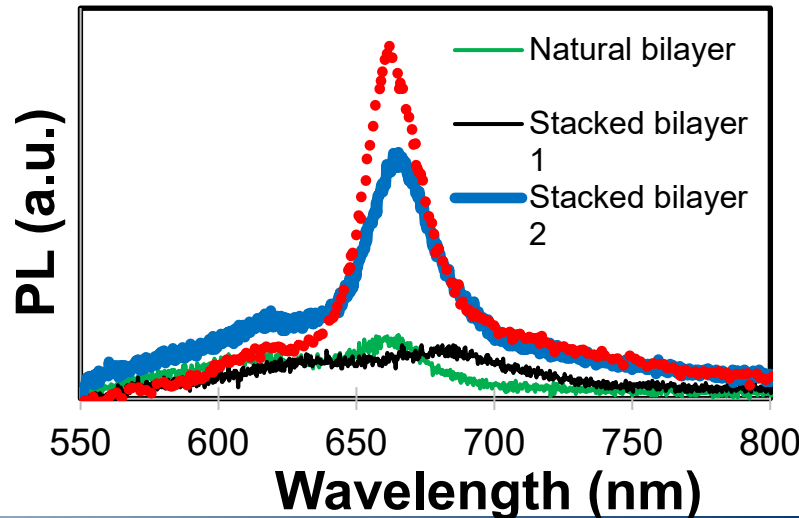


450 nm illumination



- Substrate
- 1 layer
- 2 layer, close
- 2 layer, less close

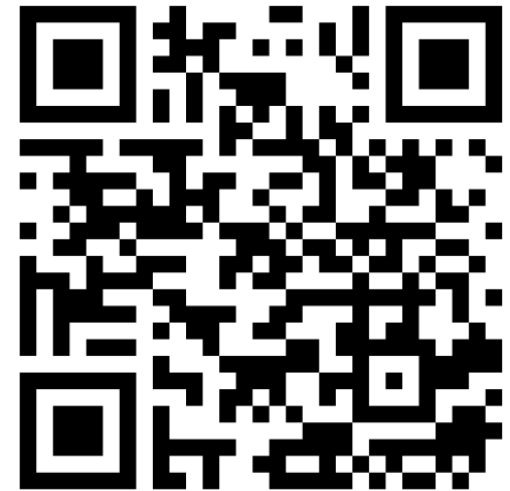
White light



Annealed stacked bilayer shows patches of optoelectronically coupled and less coupled regions – corroborated by photoluminescence (PL)

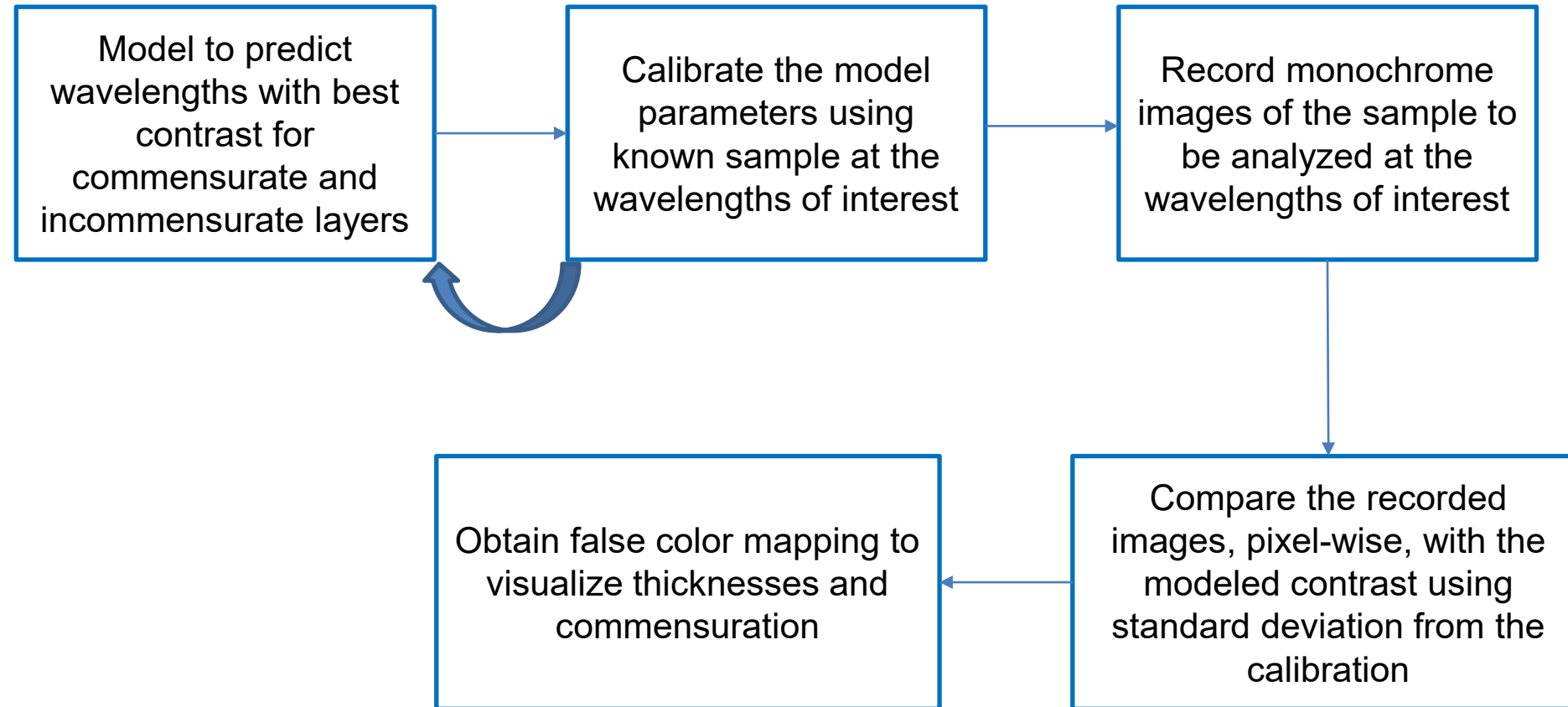
Summary and outlook

- Nanovisc: <https://nanohub.org/resources/nanovisc>
 - Viscosity extraction from thin films via color video
- 2dreflect: <https://nanohub.org/resources/2dreflect>
 - Sub-monolayer-resolution characterization of 2D material stacks
- Possible future directions:
 - Multiplexed cell deformability characterization
 - Study curing kinetics; refractive index changes under load
- Simulation needs survey: <https://bit.ly/2VCsWRg>



Supporting slides

2dreflect: computational procedure



2dreflect: interface

User's
input
panels

The screenshot shows the 2dreflect software interface with three main sections on the left for user input and two output panels on the right.

1. Model inputs

- Substrate: Sapphire (selected), Si/SiO2
- wavelength: 450nm
- 2D material: MoS2
- Calculate theoretical contrast: Done! (sapphire)
- Mono and bilayer contrast: 1;1.3256;1.7282

2. Experimental inputs

- Select Background Image: Background Image
- Select Material Image: Material Image

3. Identify layer number and area percentage

- Threshold: 0.13
- Recommended: 0.1-0.15
- Do it

Image

- Legend: substrate (black), 1 layer (red), 2 layer (green), 3 layer (blue), 4 layer (grey), >4 layer (white)

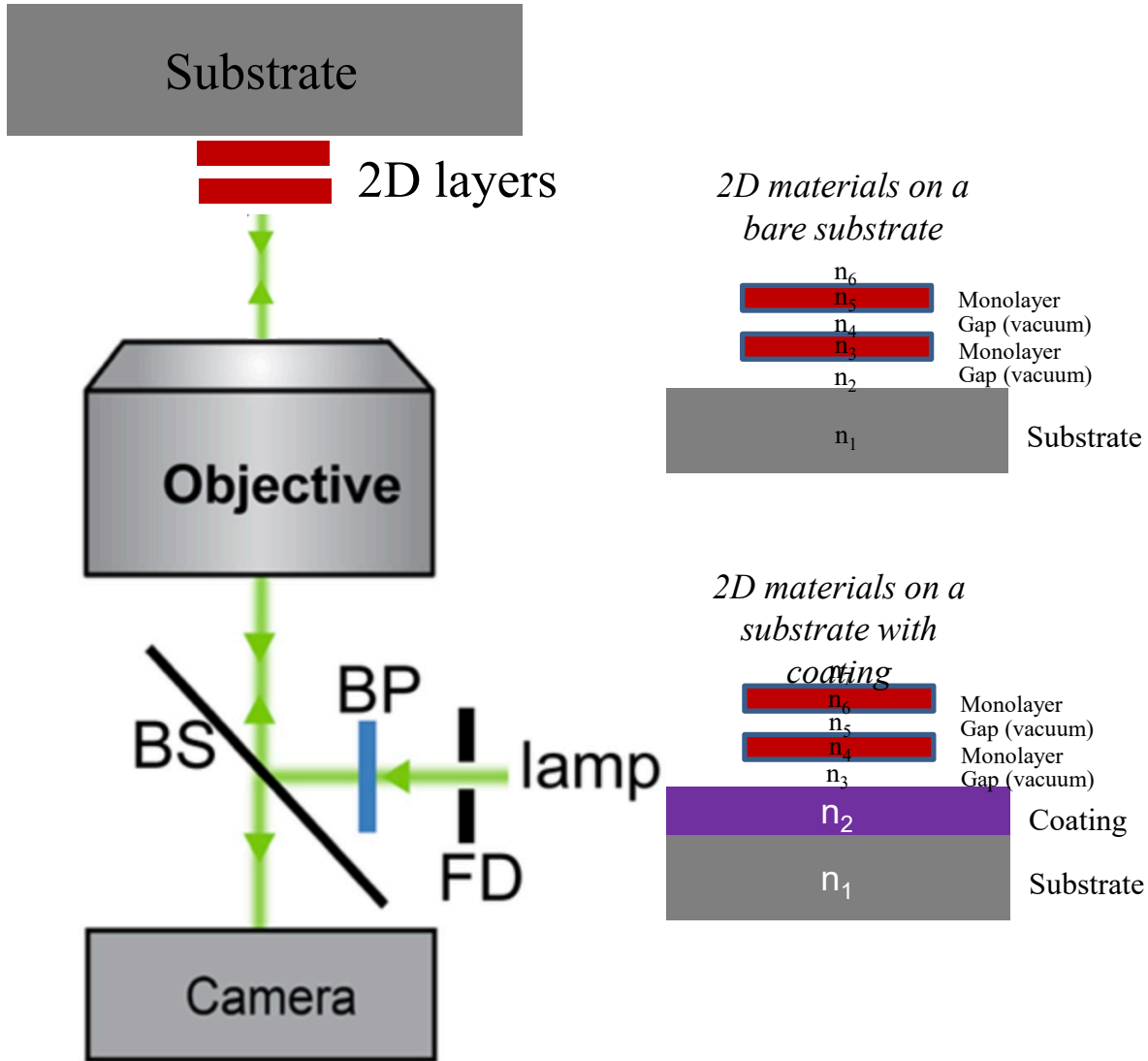
Plot

Areal percentage

Layer Count	Percentage
1 layer	~10%
2 layers	~1%
3 layers	~1%
4 layers	~1%
>4 layers	~1%

Tool's
output
panels

Reflectance-based characterization of 2D stacks



The contrast of the 2D materials is calculated using transfer matrix formulation:

Transfer matrix at interfaces

$$T^{12} = \frac{1}{t_{12}} \begin{bmatrix} 1 & r_{12} \\ r_{12} & 1 \end{bmatrix}$$

Fresnel coefficients

$$r_{12} = \frac{n_1 - n_2}{n_1 + n_2}, t_{12} = \frac{2n_1}{n_1 + n_2}$$

Transfer matrix of the layer

$$T^2 = \begin{bmatrix} e^{i\varphi} & 0 \\ 0 & e^{-i\varphi} \end{bmatrix}$$

Phase shift

$$\varphi = \frac{2\pi}{\lambda} n_2 d_2$$

With r , t being reflection and transmission coefficients according to Fresnel's equations. The transfer matrix of the layered system is then calculated:

Transfer matrix of the system

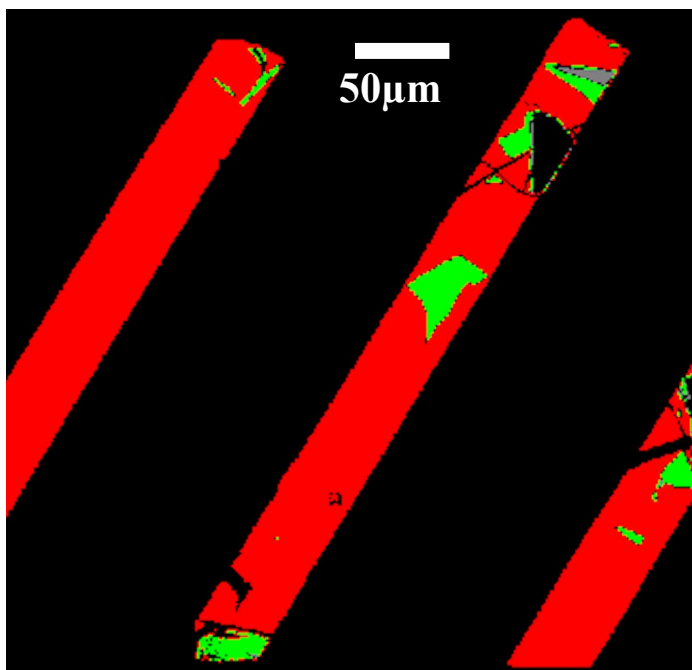
$$T^{13} = T^{12} T^2 T^{23}$$



Intensities and contrasts

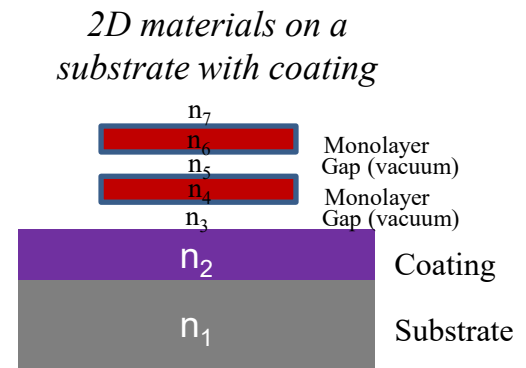
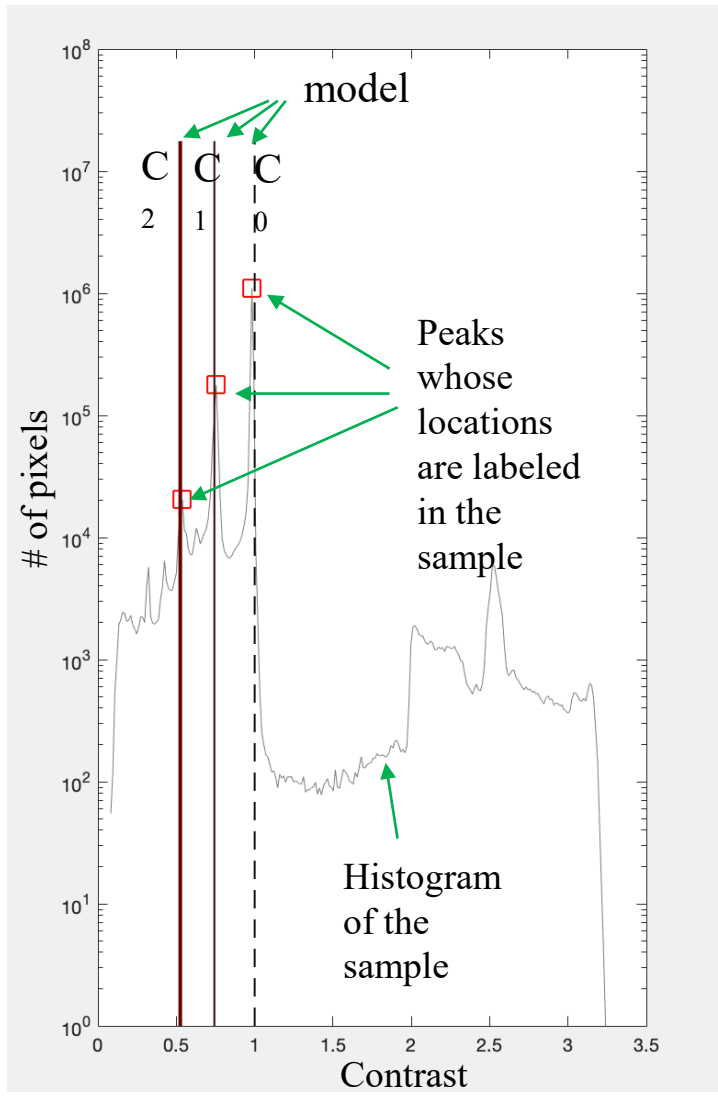
2dreflect: calibrating for the uncertainties in the substrate

Calibration sample



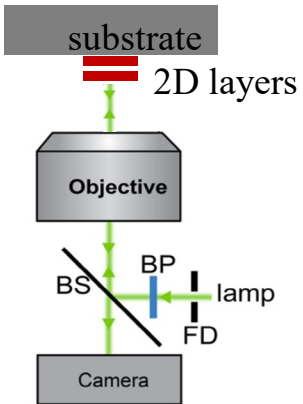
- substrate
- 1 layer
- 2 layers
- ≥ 3 layer

Thicknesses verified by PL and AFM

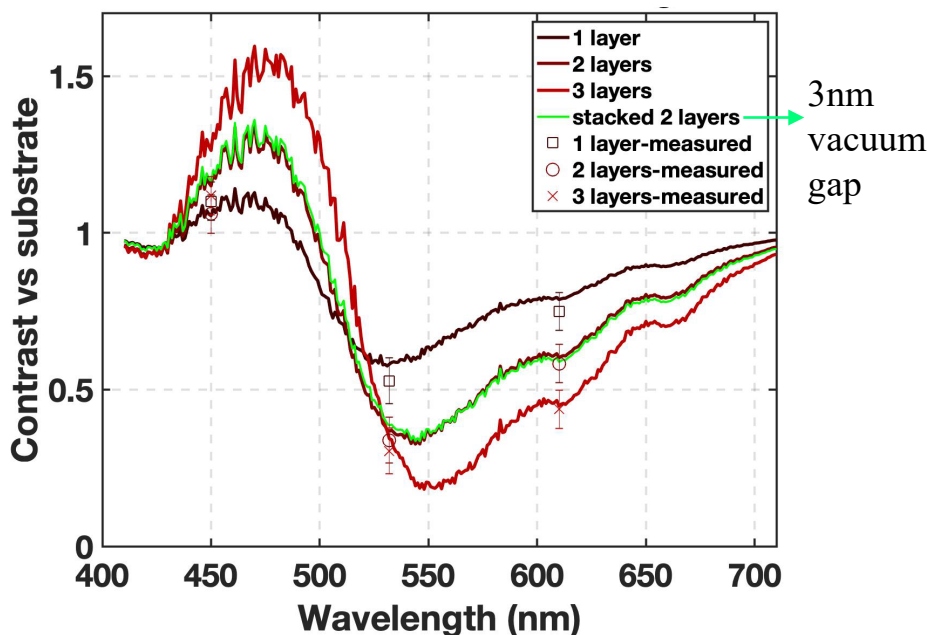
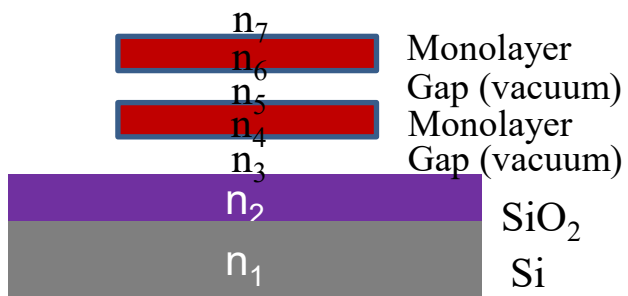


- Calibrate for:
- Coating diffusive boundary with substrate
 - Coating pure thickness
 - Gap with the coating/substrate
- Adjust until the modeled levels overlap with the peaks
- Record standard deviation of the measured levels

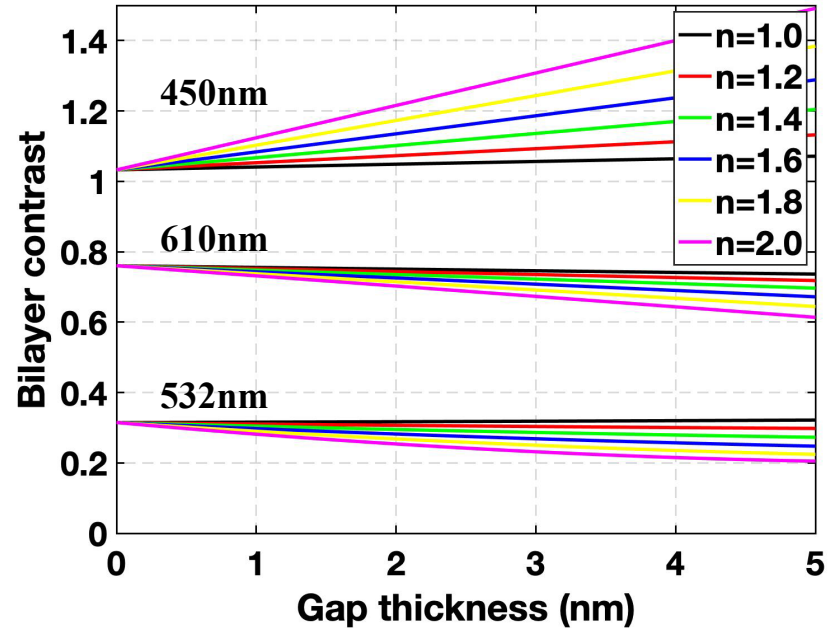
2dreflect: experimental setup and modeling the effect of inter-layer gap



2D materials on a substrate with coating



260nm SiO₂/Si substrate



- 450nm illumination yields best contrast for stacked layers with inclusion
- Different SiO₂ thickness will yield best contrast for stacked layers at different wavelength